

APPLICATION DATA SHEET

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Attorney Docket Number: BUR920000077

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Application Type: utility

Title of Invention: SINGLE REACTOR, MULTI-PRESSURE CHEMICAL VAPOR
DEPOSITION FOR SEMICONDUCTOR DEVICES

Attorney Docket Number: BUR920000077

Legal Representative:

Attorney or Agent: Mr. Robert A. Walsh Esq.

Registration Number: 26516

Customer Number Correspondence Address: 000000



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